



Inventor:

KAICHIRO NAKANO, et al.

Serial No.:

09/036,219

Filed:

March 6, 1998

Title:

CHEMICALLY AMPLIFIED RESIST LARGE IN

TRANSPARENCY AND SENSITIVITY TO EXPOSURE LIGHT

LESS THAN 248 NANOMETER WAVELENGTH AND

PROCESS OF FORMING MASK

Examiner:

J. CHU

**Group Art Unit:** 

1752

May 21, 1999

Box Non-Fee Amendment Assistant Commissioner for Patents Washington, D. C. 20231

RECEIVED NAY 2.7 1999

GROUP 1707

## AMENDMENT

SIR:

Responsive to the Office Action dated April 27, 1999, please amend the application as follows:

IN THE CLAIMS:

Please cancel claims 2, 4, 7 and 8 without prejudice.

## REMARKS

In the outstanding Office Action restriction has been issued to elect the claims between claims 1-8, drawn to resist composition, classified in claim 430, subclass 270.1 and claims 9-20, drawn to process of use, classified in class 430, subclass 325.

In addition an election requirement to elect a single species has been issued by the Examiner.

Any fee due with this paper, not fully covered by an enclosed check, may be charged on Deposit Acct. No. 08-1634